

Refine Search

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Terms	Documents
L20 and imide	1

Database:	US Pre-Grant Publication Full-Text Database
	US Patents Full-Text Database
	US OCR Full-Text Database
	EPO Abstracts Database
	JPO Abstracts Database
	Derwent World Patents Index
	IBM Technical Disclosure Bulletins

Search:

Search History

DATE: Friday, May 21, 2004 [Printable Copy](#) [Create Case](#)

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side by side

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result set

DB=USPT; PLUR=YES; OP=ADJ

<u>L21</u>	L20 and imide	1	<u>L21</u>
<u>L20</u>	L3 and membrane	3	<u>L20</u>
<u>L19</u>	L3 and polyimide	0	<u>L19</u>
<u>L18</u>	L10 and potassium iodide	0	<u>L18</u>
<u>L17</u>	L10 and polymer and membrane	1	<u>L17</u>
<u>L16</u>	L10 and polyimide	0	<u>L16</u>
<u>L15</u>	L110 and irradiation	0	<u>L15</u>
<u>L14</u>	L110 and irradiation	0	<u>L14</u>
<u>L13</u>	L110 and irradiation	0	<u>L13</u>
<u>L12</u>	L9 and radiation	199	<u>L12</u>
<u>L11</u>	L10 and I3	0	<u>L11</u>
<u>L10</u>	L9 and reducing agent	13	<u>L10</u>
<u>L9</u>	stop etching	1224	<u>L9</u>
<u>L8</u>	I3 and stop same etching	0	<u>L8</u>

<u>L7</u>	L3 and reducing agent	0	<u>L7</u>
<u>L6</u>	L3 and stop liquid	0	<u>L6</u>
<u>L5</u>	L3 and stop same agent	0	<u>L5</u>
<u>L4</u>	L3 and erradiation	0	<u>L4</u>
<u>L3</u>	l1 and etching	3	<u>L3</u>
<u>L2</u>	L1 and etch?	0	<u>L2</u>
<u>L1</u>	210/500.39.ccls.	144	<u>L1</u>

END OF SEARCH HISTORY